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Applicant(s): Cline et

Scrial No.:10/711,953

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Cline et al.

Examiner: Chen, Eric Brice

Art Unit: 1765

Filed: 10/15/2004

Docket No.: BUR920040122US1

Title: DEEP TRENCH FORMATION IN SEMICONDUCTOR DEVICE FABRICATION

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

REQUEST FOR RECONSIDERATION

Sir:

This Request for Reconsideration is in response to the Final Office Action mailed January 26, 2006.